Agorney Docket: 081468-0307456
Client Reference: P-1794.000-US

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:

Confirmation Number: 2894

BANINE ET AL.

Application No.: 10/747,613

Group Art Unit: 2851

Filed: December 30, 2003

Examiner: Della J. Rutledge

Title: LITHOGRAPHIC APPARATUS AND RADIATION SOURCE COMPRISING A DEBRIS-MITIGATION SYSTEM AND METHOD FOR MITIGATING DEBRIS PARTICLES

IN A LITHOGRAPHIC APPARATUS

## **COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE**

Mail Stop Issue Fee Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In the Office Action dated February 24, 2006, the Examiner has set forth "Reasons for Allowance." Applicants respectfully traverse these Reasons. Specifically, it is submitted that the subject matter of the allowed claims are patentable for their respective recitations of claimed combinations as a whole. That is, the patentability of the claims rests on the combination of recited elements and limitations. As such, Applicants submit that no one element or limitation in particular should be deemed to impart or be required for patentability of the claims. Furthermore, Applicants also submit that the dependent claims are allowable not only for their dependence on the allowed independent claims, but also for the additional subject matter recited in each of those dependent claims.

Respectfully submitted,

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Date: December 12, 2006

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